IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the subject application.

1. (Currently Amended) A manufacturing method of a display device in a plasma treatment chamber comprising the step of:

forming a wiring by partially etching a conductor film over a substrate by discharging a plasma to the plasma treatment chamber from a plasma treatment means having one set of electrodes contained therein for generating the plasma at a pressure of 5 to 800 Torr from a reactive gas introduced to the plasma treatment means[[,]];

~~wherein~~ providing the plasma treatment ~~means is provided~~ in the plasma treatment chamber[[,]];

~~wherein~~ providing one electrode of the set of electrodes which surrounds the other electrode of the set of electrodes[[,]]; and

providing a distal portion of the one electrode of the set of electrodes being toward the other electrode of the set of electrodes line,

wherein [[a]] the distal portion of ~~each of the other electrode~~ the one electrode of the set of electrodes has a sharp angle shape.

2. (Currently Amended) A manufacturing method of a display device in a plasma treatment chamber comprising the step of:

forming a wiring by partially etching a conductor film over a substrate by discharging a plasma to the plasma treatment chamber from a plasma treatment means having a plurality of sets of electrodes contained therein for generating the plasma at a pressure of 5 to 800 Torr from a reactive gas introduced to the plasma treatment means[[,]];

~~wherein~~ providing the plasma treatment ~~means is provided~~ in the plasma treatment chamber[[,]];

~~wherein~~ providing one electrode of the plurality of sets of electrodes which surrounds the other electrode of the plurality of sets of electrodes, respectively[[,]]; and

providing a distal portion of the one electrode of the plurality of sets of electrodes being toward the other electrode of the plurality of sets of electrodes line, respectively,

wherein [[a]] the distal portion of ~~each of the other electrode~~ the one electrode of the plurality of sets of electrodes has a sharp angle shape.

3. (Canceled)

4. (Currently Amended) A manufacturing method of a display device comprising the steps of:

forming a conductor film over a substrate;

forming a resist mask over the conductor film; [[and]]

partially etching the conductor film at a pressure of 5 to 800 Torr by discharging a plasma to a plasma treatment chamber from a plasma treatment means having one set of electrodes contained therein for generating the plasma from a reactive gas introduced to the plasma treatment means, over the resist mask thereby forming a wiring[[,]];

~~wherein~~ providing the plasma treatment ~~means is provided~~ in the plasma treatment chamber[[,]];

~~wherein~~ providing one electrode of the set of electrodes which surrounds the other electrode of the set of electrodes[[,]]; and

providing a distal portion of the one electrode of the set of electrodes being toward the other electrode of the set of electrodes line,

wherein [[a]] the distal portion of ~~each of the other electrode~~ the one electrode of the set of electrodes has a sharp angle shape.

5. (Currently Amended) A manufacturing method of a display device comprising the steps of:

forming a conductor film over a substrate;

forming a resist mask over the conductor film; [[and]]

partially etching the conductor film at a pressure of 5 to 800 Torr by discharging a plasma

to a plasma treatment chamber from a plasma treatment means having a plurality of sets of electrodes contained therein for generating the plasma from a reactive gas introduced to the plasma treatment means, over the resist mask thereby forming a wiring[[,]];

~~wherein~~ providing the plasma treatment ~~means is provided~~ in the plasma treatment chamber[[,]];

~~wherein~~ providing one electrode of the plurality of sets of electrodes which surrounds the other electrode of the plurality of sets of electrodes, respectively[[,]]; and

providing a distal portion of the one electrode of the plurality of sets of electrodes being toward the other electrode of the plurality of sets of electrodes line, respectively,

wherein [[a]] the distal portion of ~~each of the other electrode~~ the one electrode of the plurality of sets of electrodes has a sharp angle shape.

6. (Currently Amended) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the substrate has a size of 1,000 x 1,200 [[mm2]] mm^2 or more.

7. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the plasma treatment means scans the substrate in one direction.

8. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the plasma treatment means alternately scans the substrate in a row direction and in a column direction.

9. (Previously Presented) The manufacturing method of the display device according to any of claims 4 and 5, wherein the resist mask is formed by use of liquid droplet jetting means.

10-11. (Canceled)

12. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, further comprising:

moving the plasma treatment means along a rail.